

Digital Integrated Circuit (IC) Layout and Design - Week 3, Lecture 5

- <http://www.ee.ucr.edu/~rlake/EE134.html>

Reading and Prelab

- Week 1 - Read Chapter 1 of text.
- Week 2 - Read Chapter 2 of text.
- Week 3 - Read Chapter 3 of text.
- Prelab - Lab 1.
 - Read insert A of text, pp. 67 - 71.
 - The lab will make more sense if you read this before lab.
 - There is nothing to turn in.

Agenda

□ Last Lecture

- Design rules
- Layout and Design
- Ties to V_{DD} and GND
- Padframes
- Pin Packages

□ Today's Lecture

- Contacts
- Basic MOS transistor operation
- Large-signal MOS model for manual analysis
- The CMOS inverter

EE134

3

Course Emphasis / Design Styles

□ Physical design of CMOS digital ICs

□ Application Specific IC (ASIC)

- **Full Custom (What we are doing)**
 - Most flexible approach
 - Higher speed
 - Smaller designs
 - Expensive
 - Requires device-level (i.e. transistor level) knowledge
 - Push limits of a technology - must understand parasitics: stray C, L, pn jns., BJTs, breakdown, stored charge, latch-up, etc.
 - Used for high-volume chips - μ -processors & memory

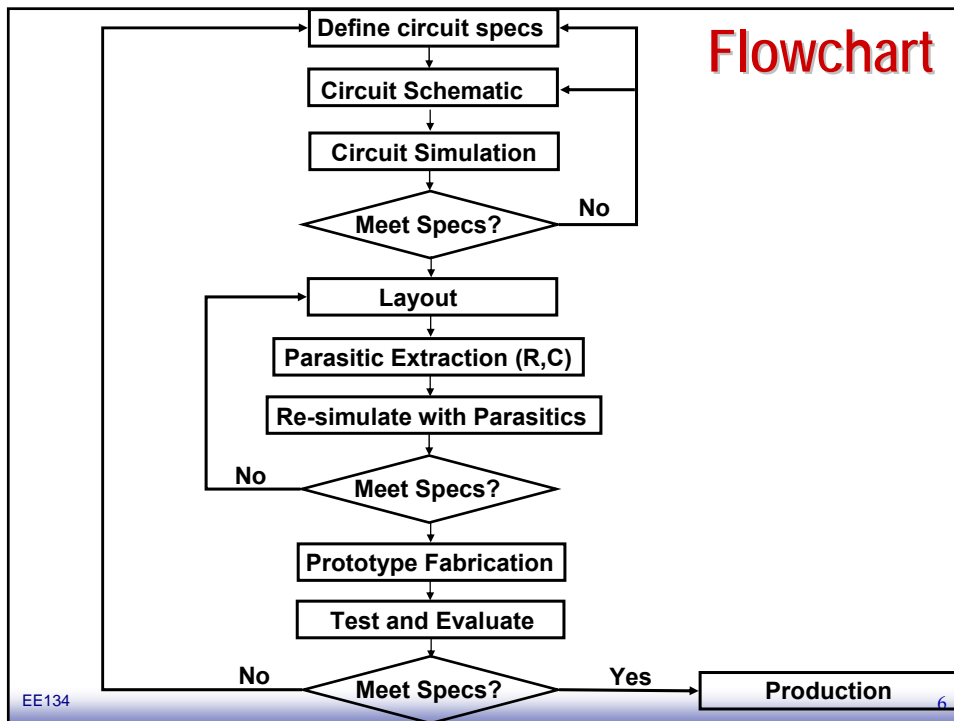
EE134

4

Design Styles (cont.)

□ ASIC (cont.)

- **Standard Cell**
 - Logic gate level
 - Low volume
 - Quick turnaround
 - Lower density
- **Gate Array (FPGA)**
 - Lowest density - speed - cost.



Tie n-well to VDD and Substrate to Ground

(a) Layout

EE134 7

Reason for GND and V_{DD} Ties

Parasitic Diodes

p-substrate

EE134 8

Contacts to Silicon

□ Ohmic Contacts

- Metal on highly doped n^+ or p^+ Si.
- What you want to pin the substrate to ground or the n-well to V_{DD} .

□ Schottky Contacts (we won't use these)

- Metal on lightly doped n or p Si.
- Creates a Schottky diode which has an I-V curve similar to a p-n junction diode.

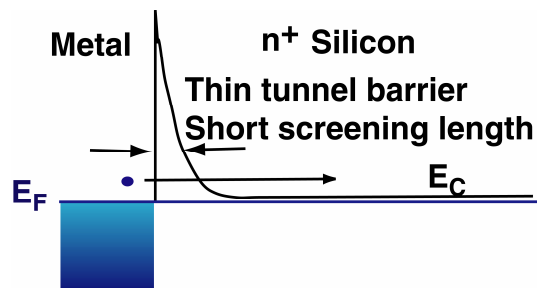
EE134

9

Ohmic contact

□ Metal on n^+ or p^+ Si.

□ Simple picture:



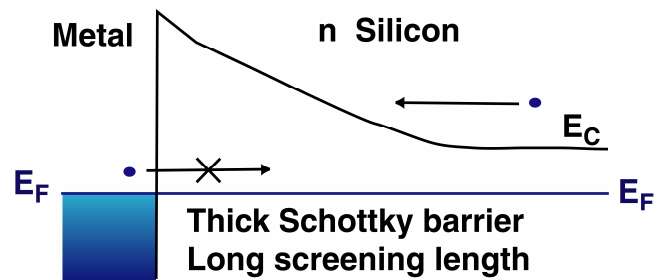
- Need heavy doping to get the ultra short screening length needed for an OHMIC contact.

EE134

10

Schottky Contact

- Metal on n or p Si.
- Simple picture:



- Light n or p doping gives long screening length giving Schottky Barrier.

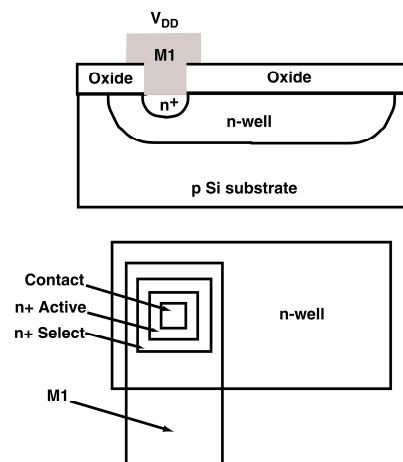
EE134

11

Ohmic Contacts for Voltage Pinning

- Ohmic contact to the n-well
- You need the

- Active and Select to define the n⁺ region.
- Contact to put hole in thick passivation oxide / nitride so that the metal contacts the Si.



EE134

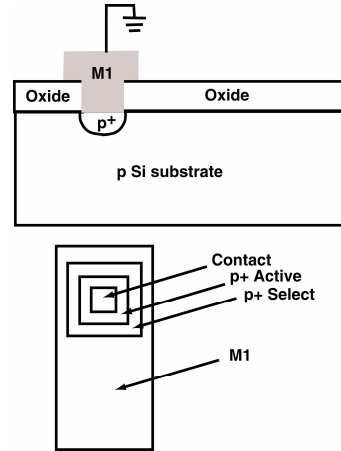
12

Ohmic Contacts for Voltage Pinning

□ Ohmic contact to the p-substrate

□ You need the

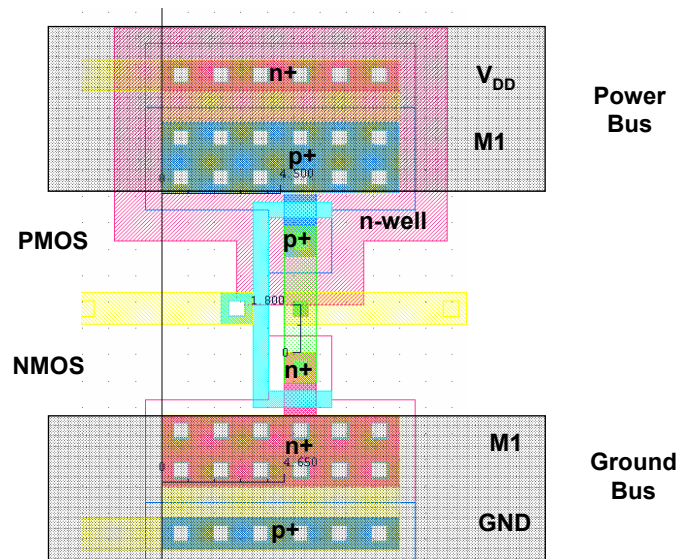
- Active and Select to define the p+ region.
- Contact to put hole in thick passivation oxide / nitride so that the metal contacts the Si.



EE134

13

Pin n-well to V_{DD} and p-substrate to GND

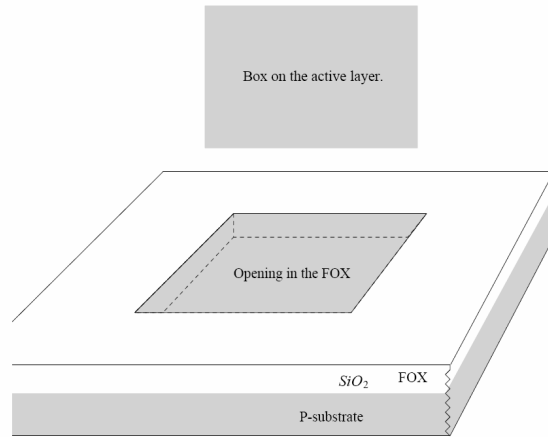


EE134

14

The Active Layer

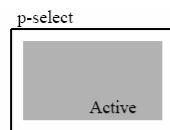
- Cut in the Field Oxide (FOX) to get down to the Si.



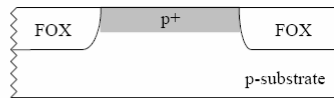
EE134

15

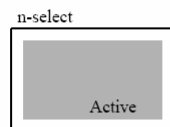
Active and Select Layers



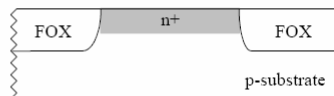
(a) Layout



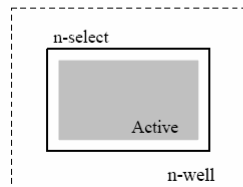
(b) Cross-sectional view for (a)



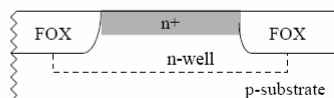
(c) Layout



(d) Cross-sectional view for (c)



(e) Layout

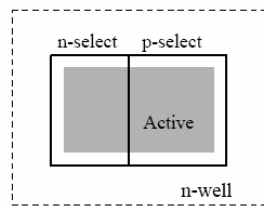


(f) Cross-sectional view for (g)

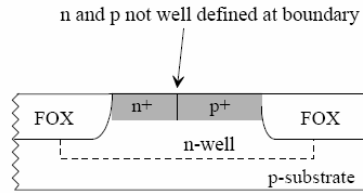
EE134

16

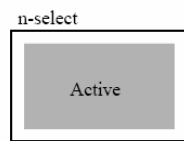
Active and Select Layers (cont)



(g) Layout

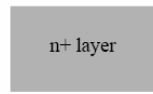


(h) Cross-sectional view for (g)



(i) two layers

Drawn as a single layer →



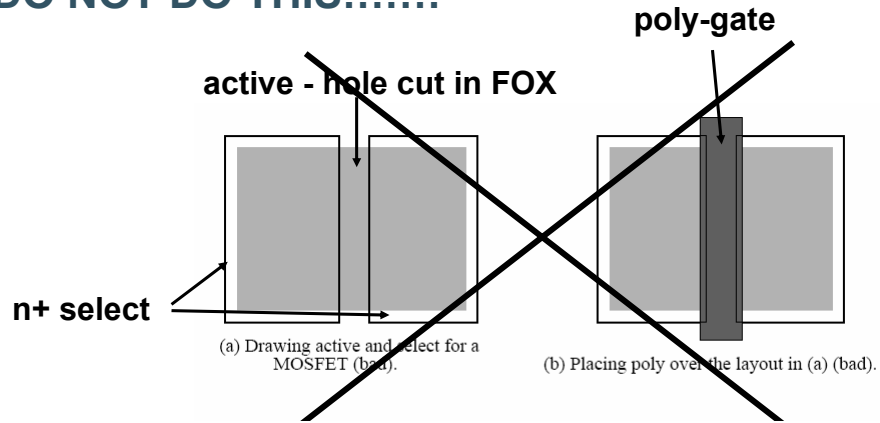
(j) Drawn as a single layer

4 Concepts to Remember:

- Need to put down an n+ region on the n-well to make an ohmic contact to the n-well.
- Need to put down a p+ region on the p-substrate to make an ohmic contact to the p-substrate.
- These are your active / select layers.
- Finally, you need a contact layer to drill through the thick oxide / nitride passivation.

BAD MOS Layout

❑ DO NOT DO THIS!!!!!!



- Self-aligned process
 - The Poly gate serves as an implant mask during the n+ implant.
 - There is no gap between the source/gate and drain/gate.

Outline

Ch. 3

- ❑ MOS Transistor
 - Basic Operation
 - Modes of Operation
 - Deep sub-micron MOS
- ❑ CMOS Inverter

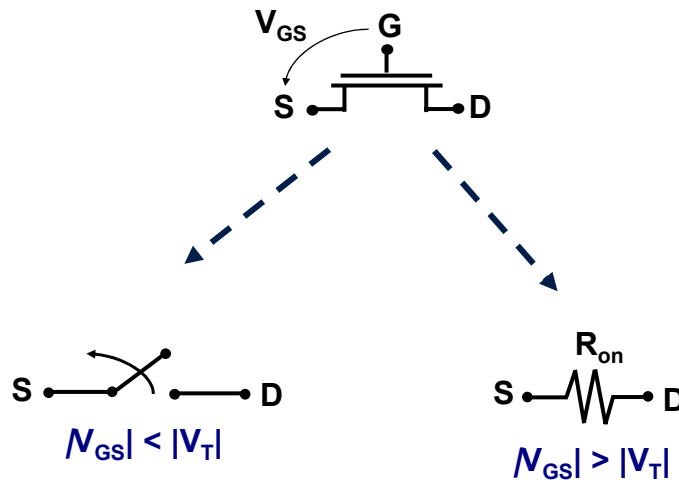


What is a Transistor?

An MOS Transistor \longleftrightarrow A Switch!

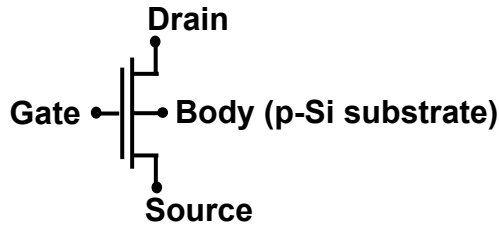


Switch Model of CMOS Transistor

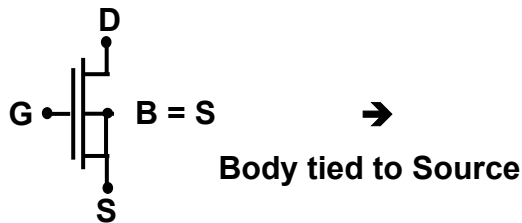
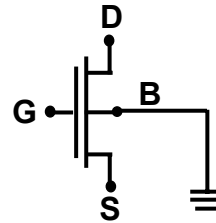


Transistor Circuit Symbols

□ NMOS



We always want



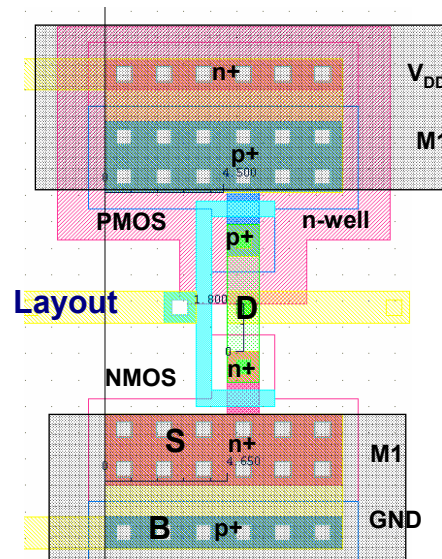
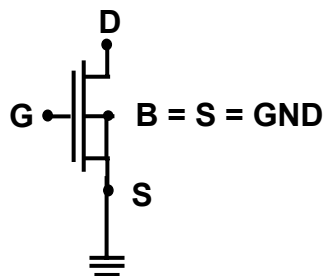
EE134

23

NMOS Body Terminal (B)

- A transistor is a 4 terminal device.

Circuit Schematic



EE134

24

Transistor Circuit Symbols

□ PMOS

We always want

Source
Gate
Body (n-well)
Drain

S
G
B
D

S
G
B = S
D

S
G
D

EE134 25

PMOS Body Terminal (B)

S = V_{DD}
G
B = S = V_{DD}
D

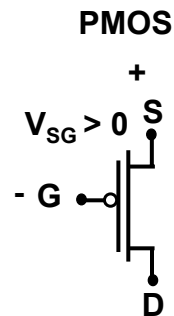
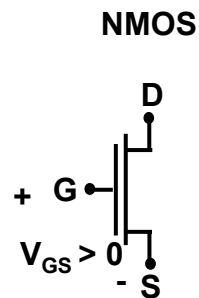
Layout

PMOS
NMOS
n+
p+
n-well
S
D
B
 V_{DD}
M1
GND

EE134 26

NMOS and PMOS

- PMOS is complementary to NMOS
- Turn it upside down and switch all signs of voltages, $V_{SD} \rightarrow V_{DS}$, $V_{GS} \rightarrow V_{SG}$.



EE134

27

Outline

Ch. 3

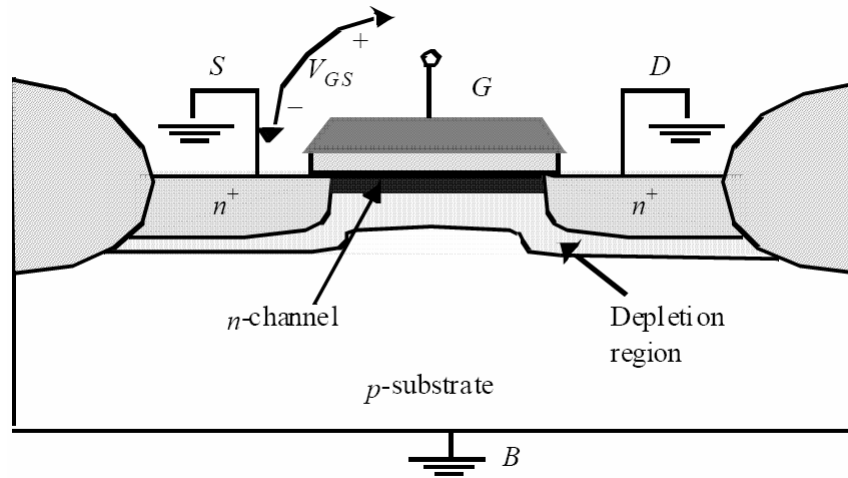
- MOS Transistor
 - Basic Operation
 - Modes of Operation
 - Deep sub-micron MOS
- CMOS Inverter



EE134

28

Threshold Voltage: Concept



EE134

29

The Threshold Voltage

$$V_T = \phi_{ms} - 2\phi_F - \frac{Q_B}{C_{ox}} - \frac{Q_{SS}}{C_{ox}} - \frac{Q_I}{C_{ox}}$$

Workfunction
Difference

Depletion Layer Charge

Body Effect Coefficient

$$V_T = V_{T0} + \gamma(\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|})$$

with

$$V_{T0} = \phi_{ms} - 2\phi_F - \frac{Q_{B0}}{C_{ox}} - \frac{Q_{SS}}{C_{ox}} - \frac{Q_I}{C_{ox}}$$

and

$$\gamma = \frac{\sqrt{2q\epsilon_{si}N_A}}{C_{ox}}$$

Fermi Potential

$$\phi_F = -\phi_T \ln\left(\frac{N_A}{n_i}\right)$$

$$\phi_T = \frac{k_B T}{q}$$

$2\phi_F \approx -0.6V$ for p-type substrates

γ is the body factor

$V_{T0} = 0.76 V$ (NMOS)

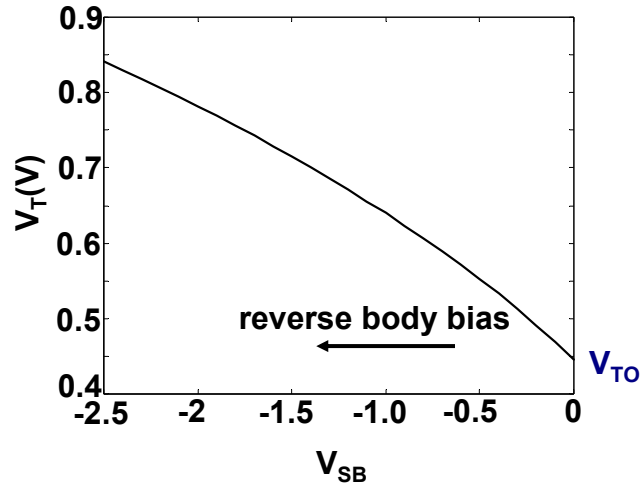
0.95 V (PMOS)

AMI C5 process

EE134

30

The Body Effect



EE134

31

The Drain Current

- Charge in the channel is controlled by the gate voltage:

$$Q_i(x) = -C_{ox}[V_{GS} - V(x) - V_T] \quad C_{ox} = \frac{\epsilon_{ox}}{t_{ox}}$$

- Drain current is proportional to charge x velocity:

$$I_D = -v_n(x) \cdot Q_i(x) \cdot W$$

$$v_n(x) = -\mu_n \cdot \xi(x) = \mu_n \frac{dV}{dx}$$

v_n = velocity; W = channel width; ξ = electric field; μ_n = mobility

EE134

32

The Drain Current

- Combining velocity and charge:

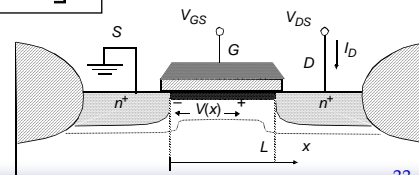
$$I_D \cdot dx = \mu_n \cdot C_{ox} \cdot W \cdot (V_{GS} - V - V_T) \cdot dV$$

- Integrating along the length of the channel from source to drain:

$$\int_0^{L_G} I_D \cdot dx = \int_0^{V_{DS}} \mu_n \cdot C_{ox} \cdot W \cdot (V_{GS} - V - V_T) \cdot dV$$

$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_T) \cdot V_{DS} - \frac{V_{DS}^2}{2} \right]$$

$$k'_n = \mu_n \cdot C_{ox} = \frac{\mu_n \cdot \epsilon_{ox}}{t_{ox}}$$



EE134

33

Outline

Ch. 3

- MOS Transistor
 - Basic Operation
 - Modes of Operation
 - Deep sub-micron MOS
- CMOS Inverter



EE134

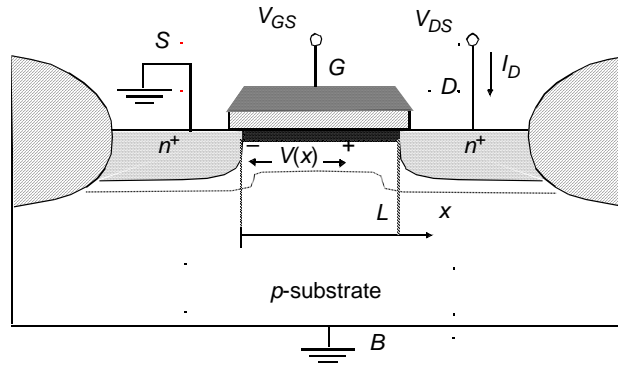
34

Transistor in Linear Mode

$$V_{GS} > V_{DS} + V_T$$

$$V_{DS} < V_{GS} - V_T$$

Device turned on ($V_{GS} > V_T$)



$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_T) \cdot V_{DS} - \frac{V_{DS}^2}{2} \right]$$

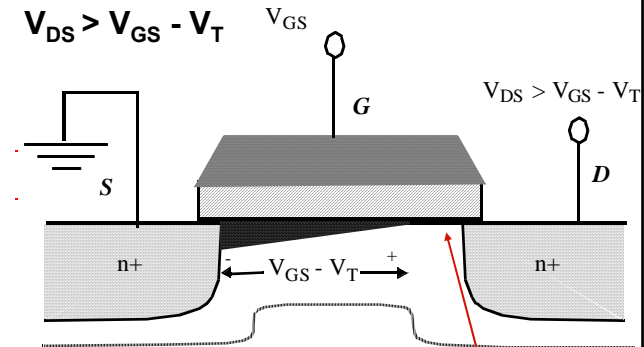
EE134

35

Transistor in Saturation

$$V_T < V_{GS} < V_{DS} + V_T$$

$$V_{DS} > V_{GS} - V_T$$



$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_T) \cdot V_{DS} - \frac{V_{DS}^2}{2} \right]$$

Pinch-off

$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \cdot \frac{W}{L} \cdot (V_{GS} - V_T)^2$$

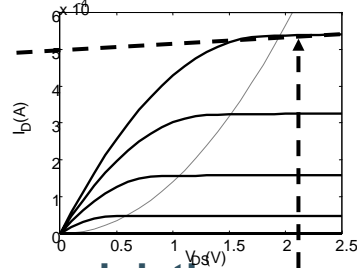
EE134

36

Saturation

- For $V_{DS} > V_{GS} - V_T$, the drain current saturates:

$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \cdot \frac{W}{L} \cdot (V_{GS} - V_T)^2$$



- Including channel-length modulation:

$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \cdot \frac{W}{L} \cdot (V_{GS} - V_T)^2 \cdot (1 + \lambda V_{DS})$$

$$\text{slope} = \lambda V_{DS} = V_{DS} / V_A$$

$$V_A = 1/\lambda = \text{Early voltage}$$

EE134

37

Modes of Operation

- Cutoff:**

$$V_{GS} < V_T$$

$$I_D = 0$$

- Resistive or Linear:**

$$V_{DS} < V_{GS} - V_T \quad \& \quad V_{GS} > V_T$$

$$I_D = \mu_n \cdot C_{ox} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_T) \cdot V_{DS} - \frac{V_{DS}^2}{2} \right]$$

- Saturation**

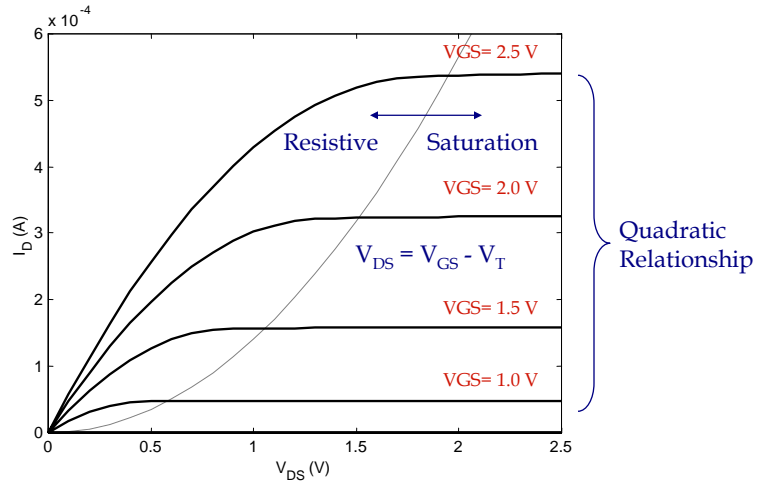
$$V_{DS} > V_{GS} - V_T \quad \& \quad V_{GS} > V_T$$

$$I_D = \frac{\mu_n \cdot C_{ox}}{2} \cdot \frac{W}{L} \cdot (V_{GS} - V_T)^2$$

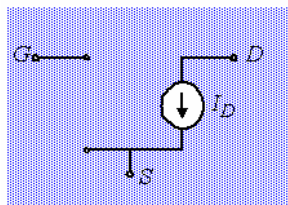
EE134

38

Current-Voltage Relations A good ol' Transistor



A model for manual analysis



$$V_{DS} > V_{GS} - V_T$$

$$I_D = \frac{k'_n W}{2 L} (V_{GS} - V_T)^2 (1 + \lambda V_{DS})$$

$$V_{DS} < V_{GS} - V_T$$

$$I_D = k'_n \frac{W}{L} \left((V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right)$$

with

$$V_T = V_{T0} + \gamma \left(\sqrt{|-2\phi_F + V_{SB}|} - \sqrt{|-2\phi_F|} \right)$$

Outline

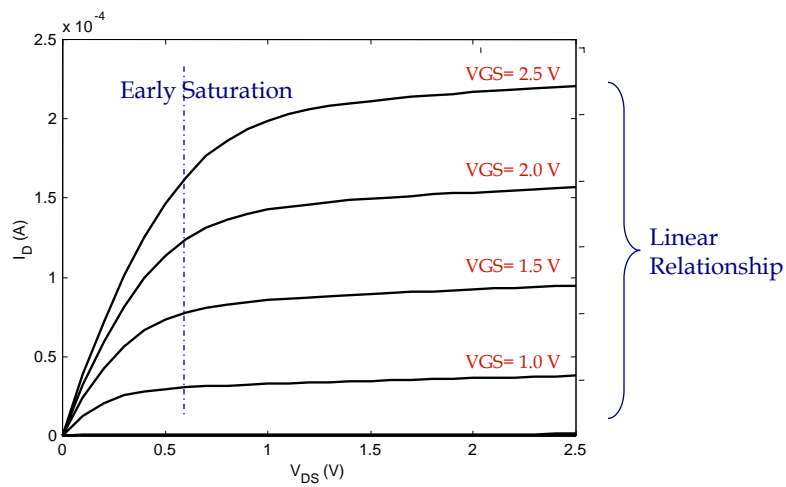
Ch. 3

- MOS Transistor
 - Basic Operation
 - Modes of Operation
 - Deep sub-micron MOS

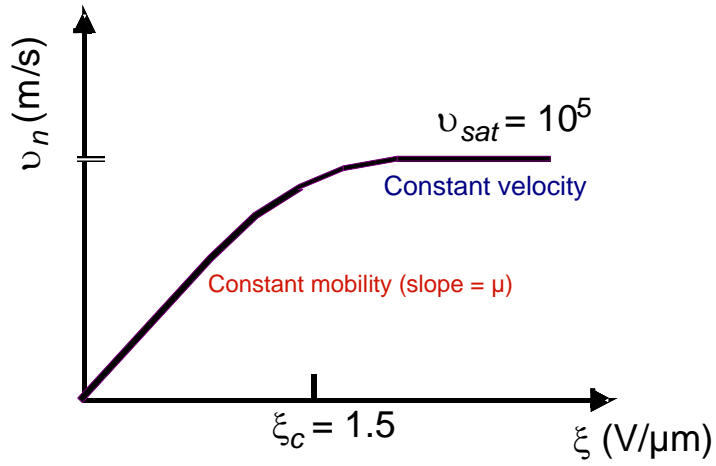
- CMOS Inverter



Current-Voltage Relations The Deep-Submicron Era



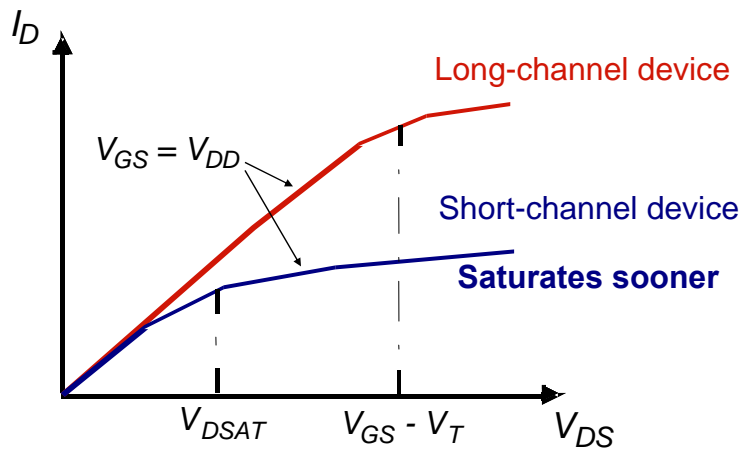
Velocity Saturation



EE134

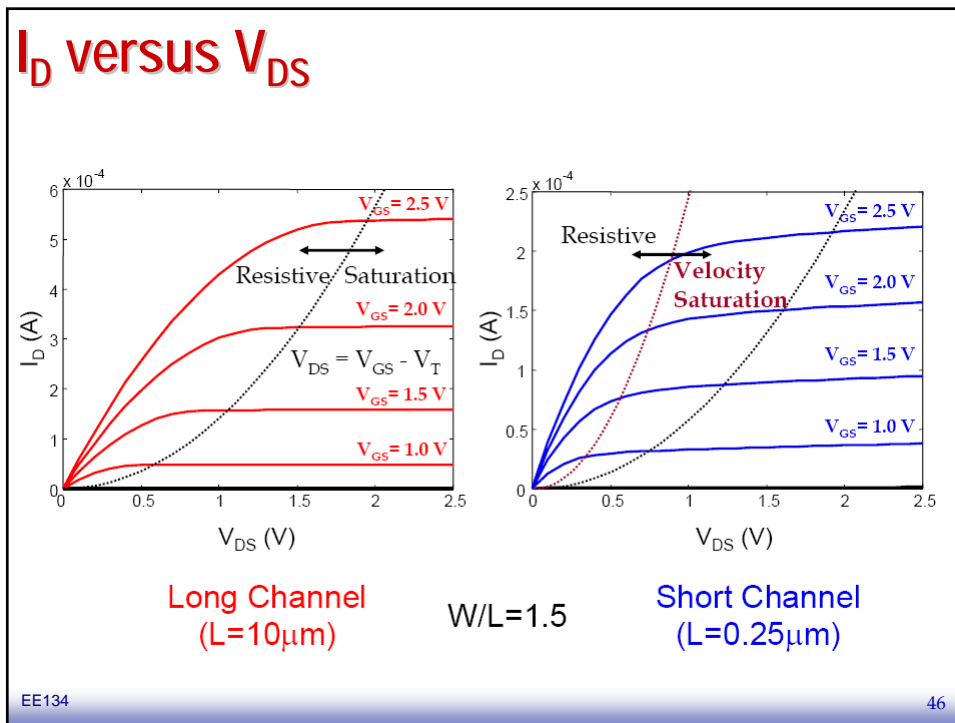
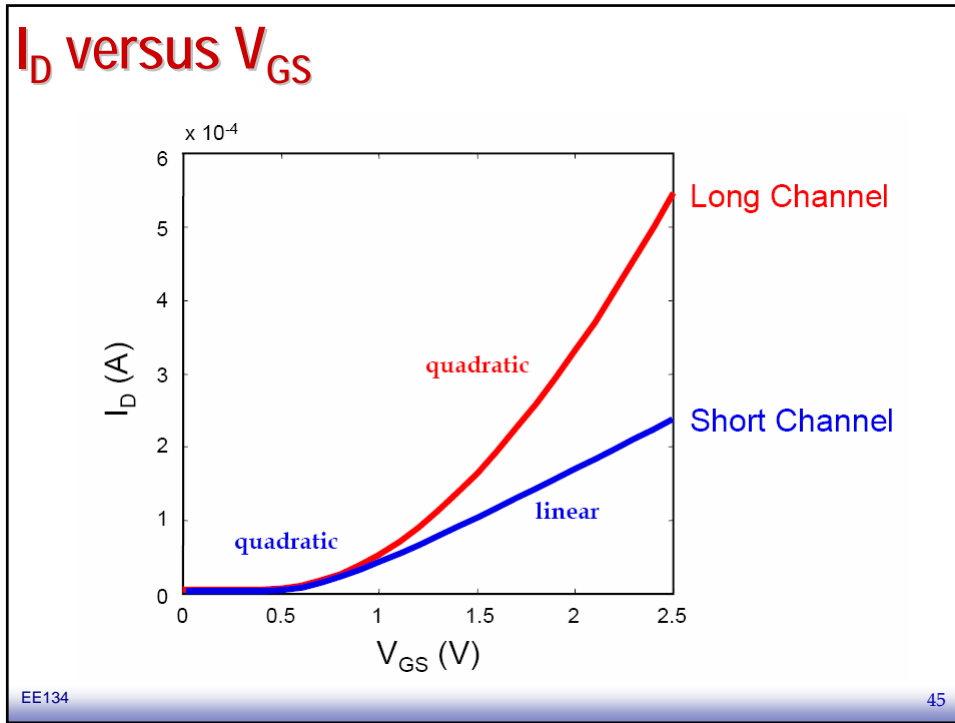
43

Velocity Saturation



EE134

44



Including Velocity Saturation

- Approximate velocity:

$$v = \frac{\mu_n \cdot \xi}{1 + \xi/\xi_c} \quad \text{for } \xi \leq \xi_c$$

$$v = v_{sat} \quad \text{for } \xi \geq \xi_c$$

μ_n chosen empirically
so that

$$\frac{\mu_n \xi_c}{2} = v_{sat}$$

→ μ_n depends on the
SPICE model.

- And integrate current again:

$$I_D = \frac{\mu_n \cdot C_{ox}}{1 + (V_{DS}/\xi_c \cdot L)} \cdot \frac{W}{L} \cdot \left[(V_{GS} - V_T) \cdot V_{DS} - \frac{V_{DS}^2}{2} \right]$$

in **deep submicron**, there are four regions of operation:
1) cutoff, (2) resistive, (3) saturation and (4) **velocity saturation**

EE134

47

Simple Cheesy Derivation for Velocity Saturation and Linear Dependence on V_{GS}

 V_{GS}

$$I_D = W \underbrace{\mu_n \frac{dV}{dx}}_{\text{velocity}} \underbrace{C'_{ox} (V_{GS} - V_{TH} - V(x))}_{\rho_{2D} \text{ (charge density)}}$$

$$I_D = W v \rho_{2D}$$

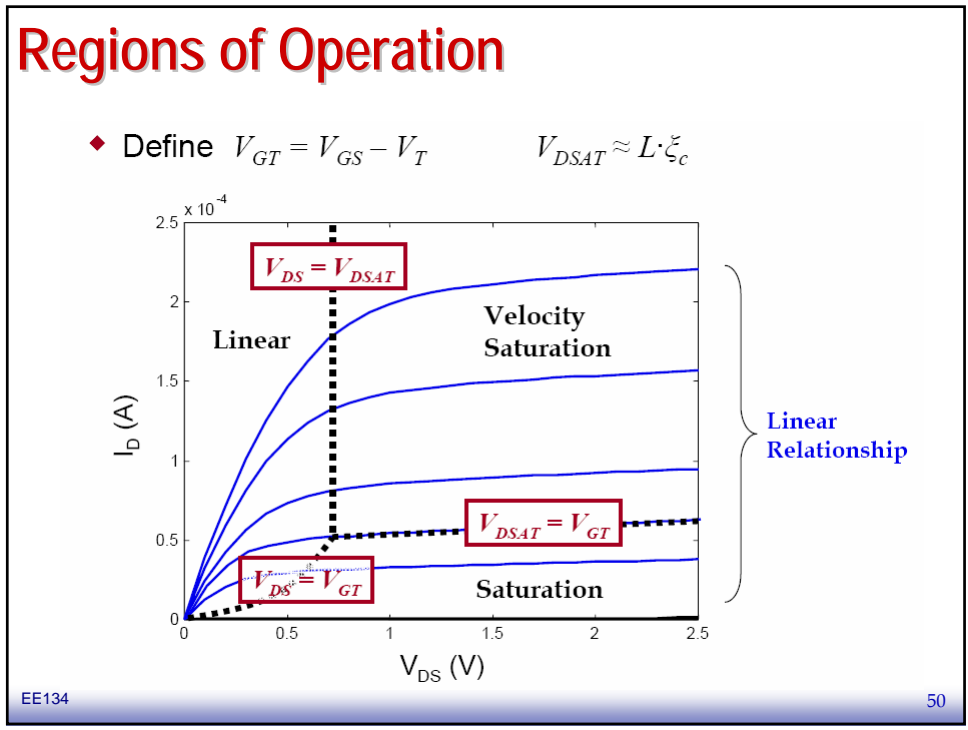
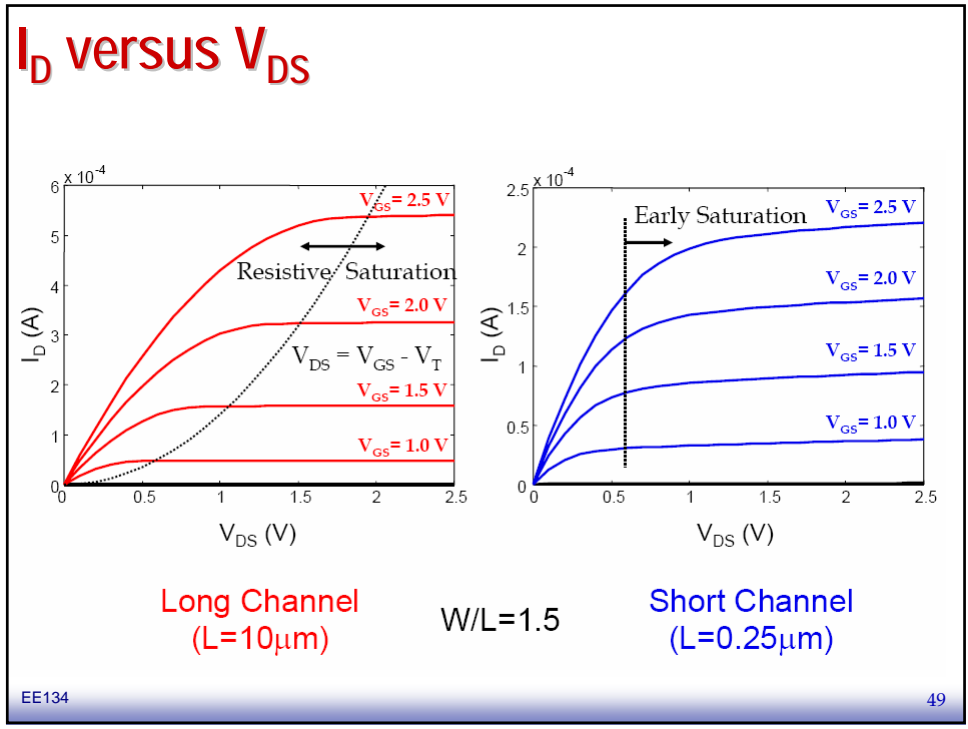
By definition, $\mu_n \equiv \frac{v}{\xi} = \frac{v}{dV/dx}$

$$I_D = W \frac{v_{sat}}{dV/dx} \frac{dV}{dx} C'_{ox} (V_{GS} - V_{TH} - V_{DS,sat})$$

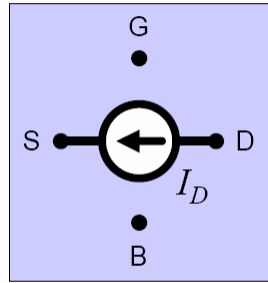
$$I_D = W v_{sat} C'_{ox} (V_{GS} - V_{TH} - V_{DS,sat})$$

EE134

48



A Unified Model for Manual Analysis



define $V_{GT} = V_{GS} - V_T$

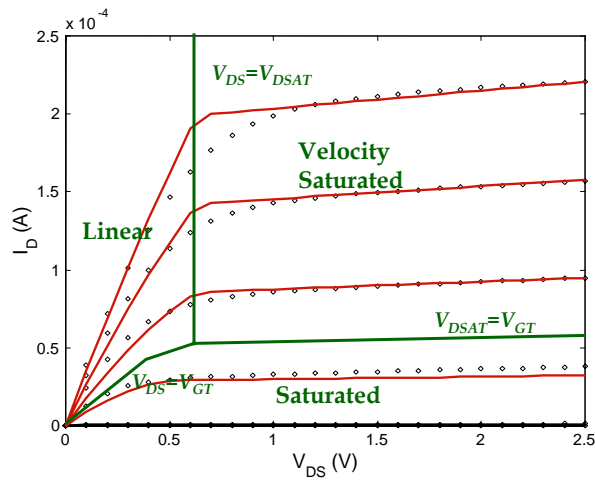
for $V_{GT} \leq 0$: $I_D = 0$

for $V_{GT} \geq 0$:

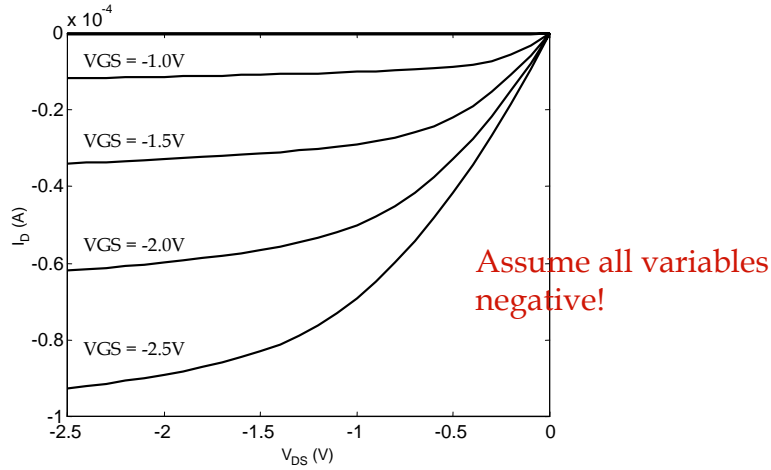
$$I_D = k' \cdot \frac{W}{L} \cdot \left(V_{GT} \cdot V_{\min} - \frac{V_{\min}^2}{2} \right) \cdot (1 + \lambda \cdot V_{DS})$$

with $V_{\min} = \min(V_{GT}, V_{DS}, V_{DSAT})$

Simple Model versus SPICE



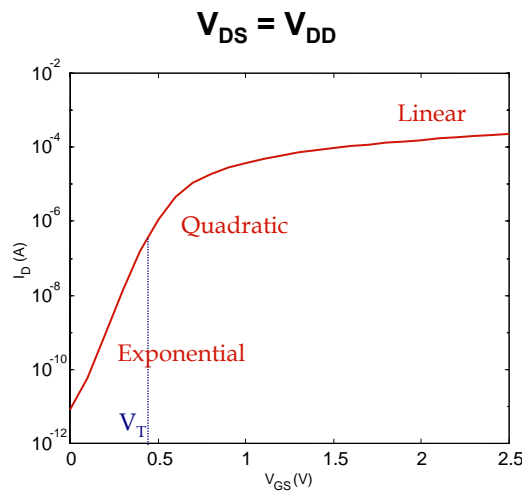
A PMOS Transistor



EE134

53

Sub-Threshold Conduction (Cut-off)



The Slope Factor

$$I_D \sim I_0 e^{\frac{qV_{GS}}{nkT}}, \quad n = 1 + \frac{C_D}{C_{ox}}$$

S is ΔV_{GS} for $I_{D2}/I_{D1} = 10$

$$S = n \left(\frac{kT}{q} \right) \ln(10)$$

Typical values for S :
60 .. 100 mV/decade

S = inverse subthreshold slope

EE134

54

Subthreshold

□ Inverse sub-threshold slope (S)

- Ideal value @ T=300K, n=1,

$$S = \frac{k_B T}{q} \ln(10) = 60 \frac{\text{mV}}{\text{decade}}$$

- For each 60 mV of V_{GS} , the current drops by a factor of 10. This is the best that you can do.
- For $V_{DD} = 0.4\text{V}$, the maximum on-off current ratio that you can have at T=300K is

$$10^{\frac{400}{60}} = 4.6 \times 10^6$$

- At 373K, the ratio is

$$10^{\frac{400}{74}} = 2.3 \times 10^5$$

EE134

55

Subthreshold

□ Current in subthreshold

$$I_D = I_S e^{\frac{V_{GS}}{nk_B T/q}} \left(1 - e^{-\frac{V_{DS}}{k_B T/q}} \right) (1 + \lambda V_{DS})$$

□ Inverse subthreshold slope definition

$$S \equiv \left(\frac{d(\log_{10} I_{DS})}{dV_{GS}} \right)^{-1} = \left(\frac{1}{\ln 10} \frac{1}{I_{DS}} \frac{dI_{DS}}{dV_{GS}} \right)^{-1}$$

$$S = \frac{nk_B T}{q} \ln 10$$

EE134

56

Subthreshold Concepts

- FETs turn off exponentially.
- Inverse subthreshold slope, S (mV/dec), is the figure of merit that tells how well they shut off.

$$S = \frac{nk_B T}{q} \ln(10) \underset{n=1}{=} \begin{cases} 60 \text{ mV/dec @ } 27^\circ \text{C} \\ 74 \text{ mV/dec @ } 100^\circ \text{C} \end{cases}$$

$$n \geq 1 \text{ and typically } \approx 1.5$$
- The maximum possible on-off current ratio is

$$\frac{I_{on}}{I_{off}} \Big|_{\max} = 10^{V_{DD}/S}$$
- 2018 ITRS node has $V_{DD} = 0.4\text{V}$ - hence the static power problem.

Know this if you are in an interview with a semiconductor co.

Transistor Model for Manual Analysis

Table 3.2 Parameters for manual model of generic 0.25 μm CMOS process (minimum length device).

	V_{TD} (V)	γ ($\text{V}^{0.5}$)	V_{DSAT} (V)	k' (A/V^2)	λ (V^{-1})
NMOS	0.43	0.4	0.63	115×10^{-6}	0.06
PMOS	-0.4	-0.4	-1	-30×10^{-6}	-0.1